

PATENT  
Customer No. 22,852  
Attorney Docket No. 08409.0025

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
 )  
Tuung Luoh ) Group Art Unit: 1754  
 )  
Application No.: 10/715,558 ) Examiner: Not yet assigned  
 )  
Filed: November 19, 2003 )  
 )  
For: METHOD OF FORMING A )  
POLYSILICON LAYER )  
COMPRISING )  
MICROCRYSTALLINE GRAINS )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicant brings to the attention of the Examiner the document listed on the attached PTO 1449. This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits for the above-referenced application.

Applicant respectfully requests that the Examiner consider the listed document and indicate that the document was considered by making appropriate notations on the attached form.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed document is material or constitute "prior art." If the Examiner applies the document as prior art

against any claim in the application and applicant determines that the cited document does not constitute "prior art" under United States law, applicant reserves the right to present to the office the relevant facts and law regarding the appropriate status of such document.

Applicant further reserves the right to take appropriate action to establish the patentability of the disclosed invention over the listed document, should the document be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

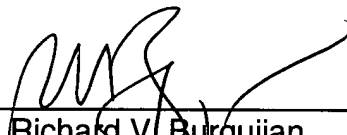
Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

Dated:

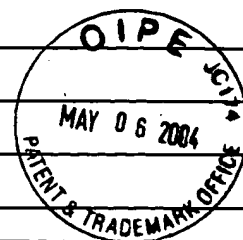
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By:

  
Richard V. Burgujian  
Reg. No. 31,744

## INFORMATION DISCLOSURE CITATION

Atty. Docket No.	08409.0025	Serial No.	10/715,558
Applicant	Tuung Luoh		
Filing Date	November 19, 2003	Group:	1754



## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate

## FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	Tuung Luoh et al., "Single-Wafer Polysilicon Engineering for the Improvement of Over Erase in a 0.18- $\mu$ m Floating-Gate Flash Memory," IEEE Transactions on Semiconductor Manufacturing, Vol. 16, No. 2, May 2003, pp. 155 - 164.

Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce